

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 2077.D1/SILICON/MBE

09/595,778  
SERIAL NO. ~~1776~~

## LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT: Grimbergen, et al.

FILING DATE: Herewith

GROUP: ~~Unknown~~ 1776

## U.S. PATENT DOCUMENTS

Examiner Initial		DOCKET NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>AWD</i>	A1*	4	1	9	8	2	6	1	4/15/80	Busta, et al.	156	626	
	A2*	4	2	0	8	2	4	0	6/17/80	Latos	156	627	
	A3*	4	4	9	3	7	4	5	1/15/85	Chen, et al.	156	626	
	A4*	4	8	4	2	6	8	3	6/27/89	Cheng, et al.	156	345	
	A5*	4	8	5	9	2	7	7	8/22/89	Barna, et al.	156	626	
	A6*	4	9	5	3	9	8	2	09/1998	Ebbing, et al.	356	357	
	A7*	4	9	7	5	1	4	1	12/04/90	Greco, et al.	156	626	
	A8*	5	0	0	2	6	3	1	03/26/91	Giapis, et al.	156	643	
	A9*	5	2	0	0	0	2	3	4/6/93	Gifford, et al.	156	626	
	A10*	5	3	6	2	3	5	6	11/8/94	Schoenborn	156	626	
	A11*	5	3	7	2	6	7	3	12/1994	Stager, et al.	438	008	
	A12*	<del>5</del>	<del>3</del>	<del>7</del>	<del>2</del>	<del>6</del>	<del>7</del>	<del>3</del>	<del>12/1994</del>	<del>Stager, et al.</del>			DUPLICATE
	A13*	5	3	9	2	1	2	4	2/21/95	Barbee, et al.	356	381	
	A14*	5	3	9	9	2	2	9	3/21/95	Stefani, et al.	156	626	
	A15*	5	4	0	3	4	3	3	4/1995	Morrison, et al.	216	060	
	A16*	5	4	0	6	0	8	0	4/11/95	Friedheim	250	309	
	A17*	5	4	4	5	7	0	5	8/29/95	Barbee, et al.	156	627.1	
	A18*	5	4	5	0	2	0	5	9/12/95	Sawin, et al.	356	382	
	A19*	5	4	5	1	2	8	9	9/19/95	Barbee, et al.	216	059	
	A20*	5	4	5	6	7	8	8	10/10/95	Barbee, et al.	156	345	
	A21*	5	4	6	7	8	8	3	11/21/95	Frye, et al.	216	060	
	A22*	5	4	7	2	5	0	8	12/1995	Saxena	118	723EE	
	A23*	5	5	3	6	3	5	9	7/1996	Kawada, et al.	438	016	
	A24	5	6	5	4	9	0	3	8/5/97	Reitman, et al.	364	651.01	
	A25	5	6	9	1	5	4	0	11/25/97	Halle, et al.	250	372	
	A26*	5	7	1	6	4	5	1	2/10/98	Hama, et al.	118	723	
	A27	5	7	4	7	3	8	0	5/5/98	Yu, et al.	438	599	
	A28*	5	7	7	0	0	9	7	6/1998	O'Neill, et al.	216	060	
	A29*	5	7	9	2	2	7	2	8/1998	Van Os, et al.	118	723R	
<i>AWD</i>	A30*	5	8	0	7	7	6	1	09/1998	Coronel, et al.	438	014	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.  
Include copy of this form with next communication to applicant.

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 2077.D1/SILICON/MBE

09/595,778  
SERIAL NO. ~~344~~

## LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT: Grimbergen, et al.

FILING DATE: Herewith

GROUP: 1746  
~~Unknown~~

## U.S. PATENT DOCUMENTS

Examiner Initial		DOCKET NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>AW</i>	A31	5	8	3	4	3	7	5	11/10/98	Chen	438	692	
<i>AW</i>	A32*	5	8	4	6	8	8	3	12/8/98	Moslehi	438	711	
	A33												
	A34												
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*Ma. Obe*

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4/16/02

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FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 2077.D1/USA/SILICON/MBE

09/595,773  
SERIAL NO. N/A

## LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT: Grimbergen, ET AL.

FILING DATE: Herewith

GROUP: Unknown 1746

## FOREIGN PATENT DOCUMENTS

		DOCKET NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES	NO
<i>Ac</i>	B1*	0	7	3	5	5	6	5	02/10/96	EP APPLICATION				
<i>Ac</i>	B2	0	7	5	6	3	1	8	1/19/97	EP APPLICATION	H01L	21/66		
<i>Ac</i>	B3*	0	7	8	8	1	3	8	08/06/97	EP APPLICATION				
	B4													
	B5													
	B6													
	B7													
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	B30													

U.S. PTO  
09/595,773  
06/16/00

EXAMINER

*Allen W. O'Brien*

DATE CONSIDERED

*7/16/02*

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 2007.D1/USA/SILICON/MBE

09/595/778  
SERIAL NO.: ~~44~~**LIST OF ART CITED BY APPLICANT**

(Use several sheets if necessary)

APPLICANT: Grimbergen, et al.

FILING DATE: Herewith

GROUP: Unknown <sup>1746</sup>**OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)**

<i>Acw</i>	C1*	International Search Report, dated February 17, 1999
<i>1</i>	C2*	Principles of Instrumental Analysis, 2 <sup>nd</sup> Ed., Skoog and West (Saunders, 1980) pages 181, 182, 193, 245
	C3*	Sofie Instruments- Product User's Manual, Digitwin
<i>1</i>	C4*	"In-Situ Control and Diagnosis of Deposition and Etch Processes is Possible Using Interferometry Combined with CCD Imaging", European Semi-Conductor, March 1995, pages 14-17
<i>Acw</i>	C5*	F. Heinrich; P. Kopperschmidt, "Online Uniformity Measurements in Large Area Plasma Assisted Etching and Deposition", Proceedings of the 10 <sup>th</sup> International Colloquium on Plasma Processes CIP '95", Antibes, France, June 11-15 1995
	C6	
	C7	
	C8	
	C9	
	C10	
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	C20	

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